



# Numerical evaluations of a new 3D stacking structure for power supply on chip

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## Abstract

- We propose the new 3D stacking structure for power supply on chip, which enable thermal insulation and heat exhausting.
- We also evaluate the proposed structure and compare proposed structure and the conventional one through numerical simulations.

## Simulation condition

### •Thermal analysis

$$\rho c \frac{\partial T}{\partial t} = \frac{\partial}{\partial x} \left( \lambda \frac{\partial T}{\partial x} \right) + \frac{\partial}{\partial y} \left( \lambda \frac{\partial T}{\partial y} \right) + Q_v$$

$\rho$ : Density,  $c$ : specific heat capacity  $T$ : temperature,  $t$ : time,  $\lambda$ : thermal conductivity,  $Q_v$ : heat generation

- Giving 1W for heating layer

## Introduction

### Power SoC

#### Merit

- Ultimate miniaturization
- Mass production

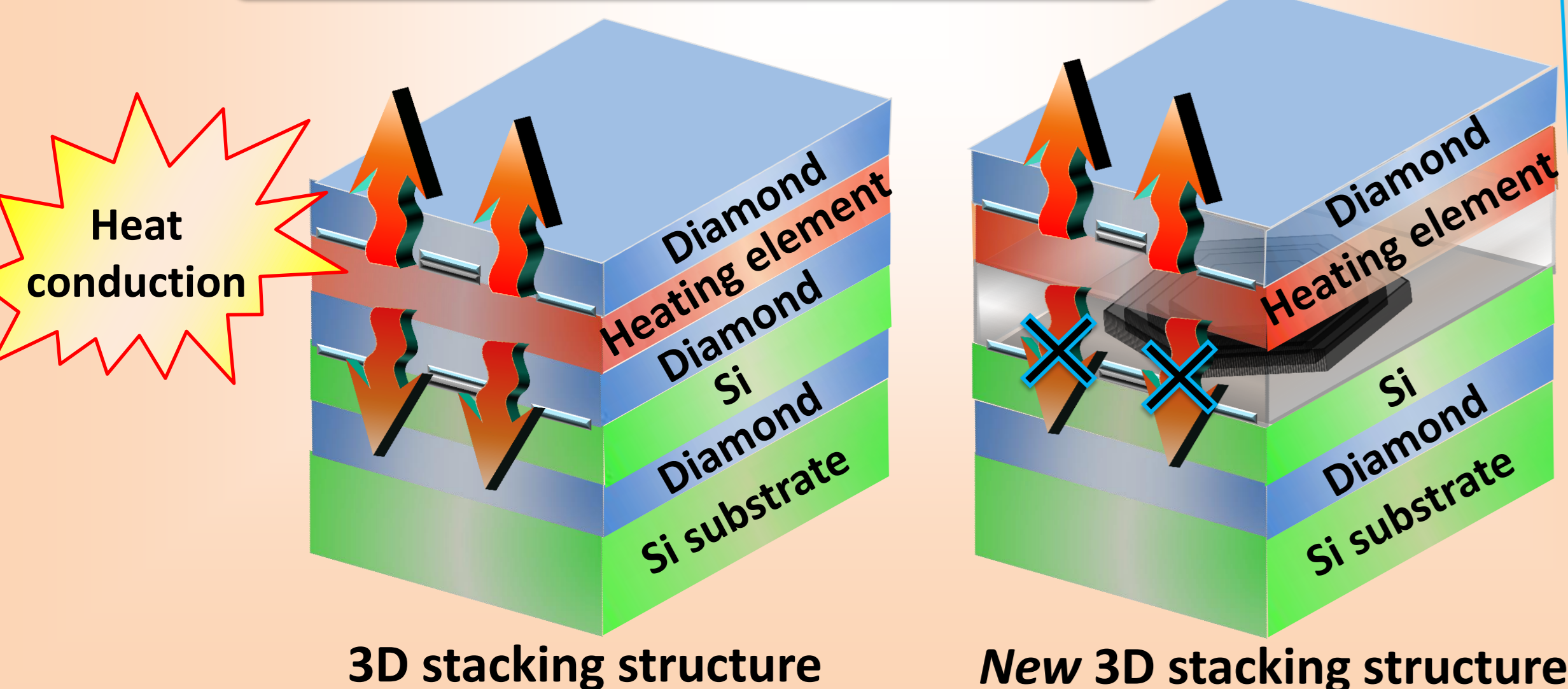
#### Challenges...

- Self heating
- High frequency switching

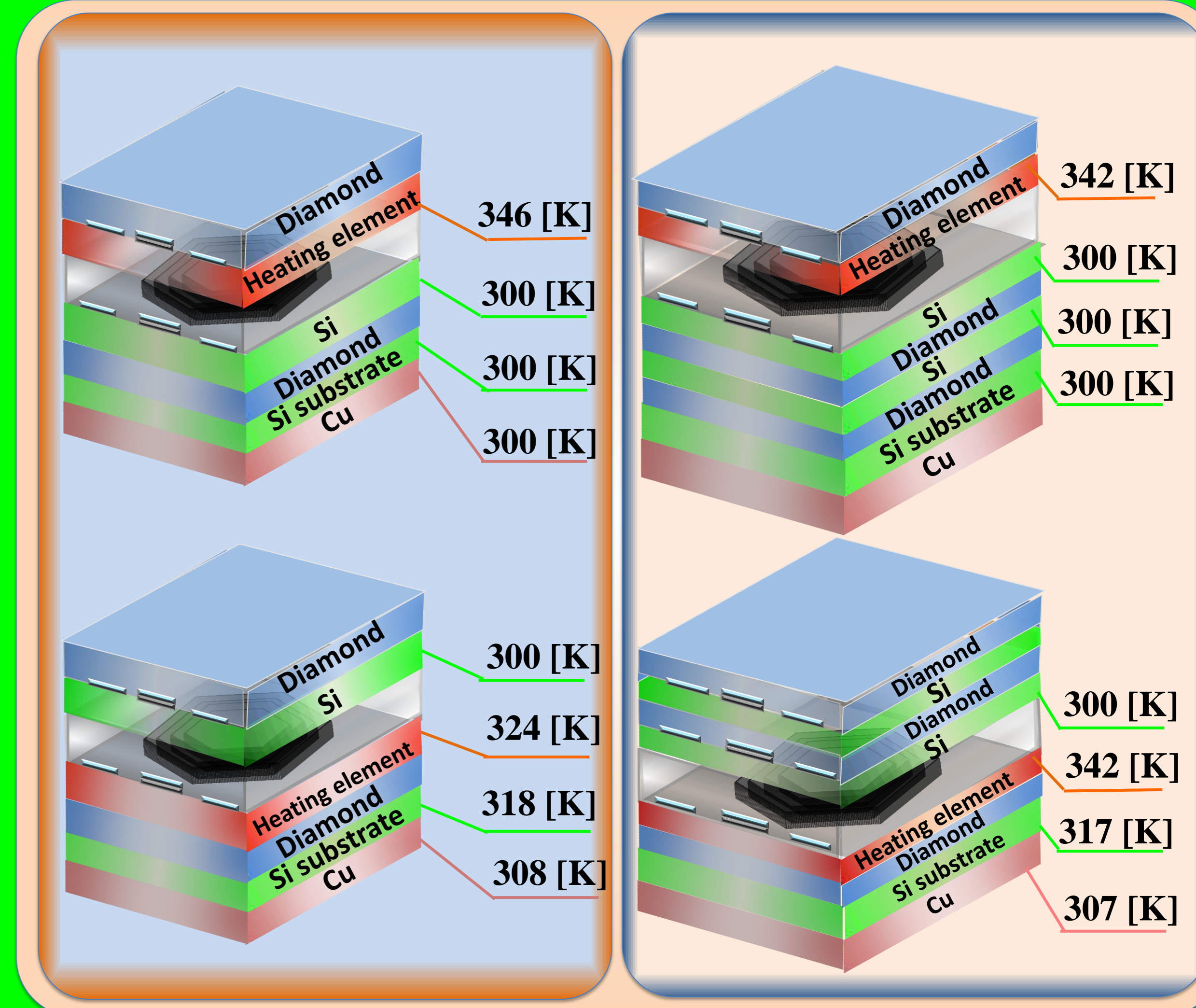
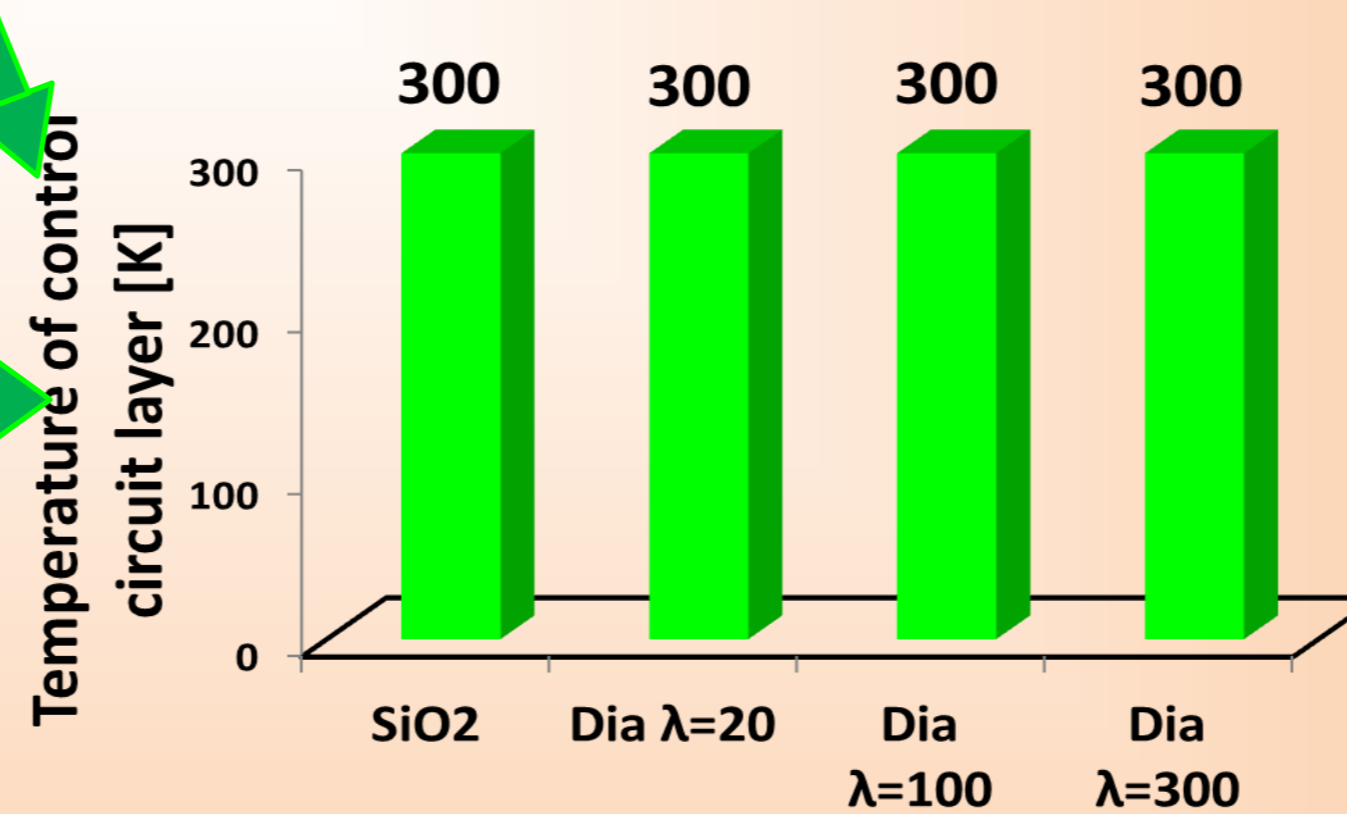
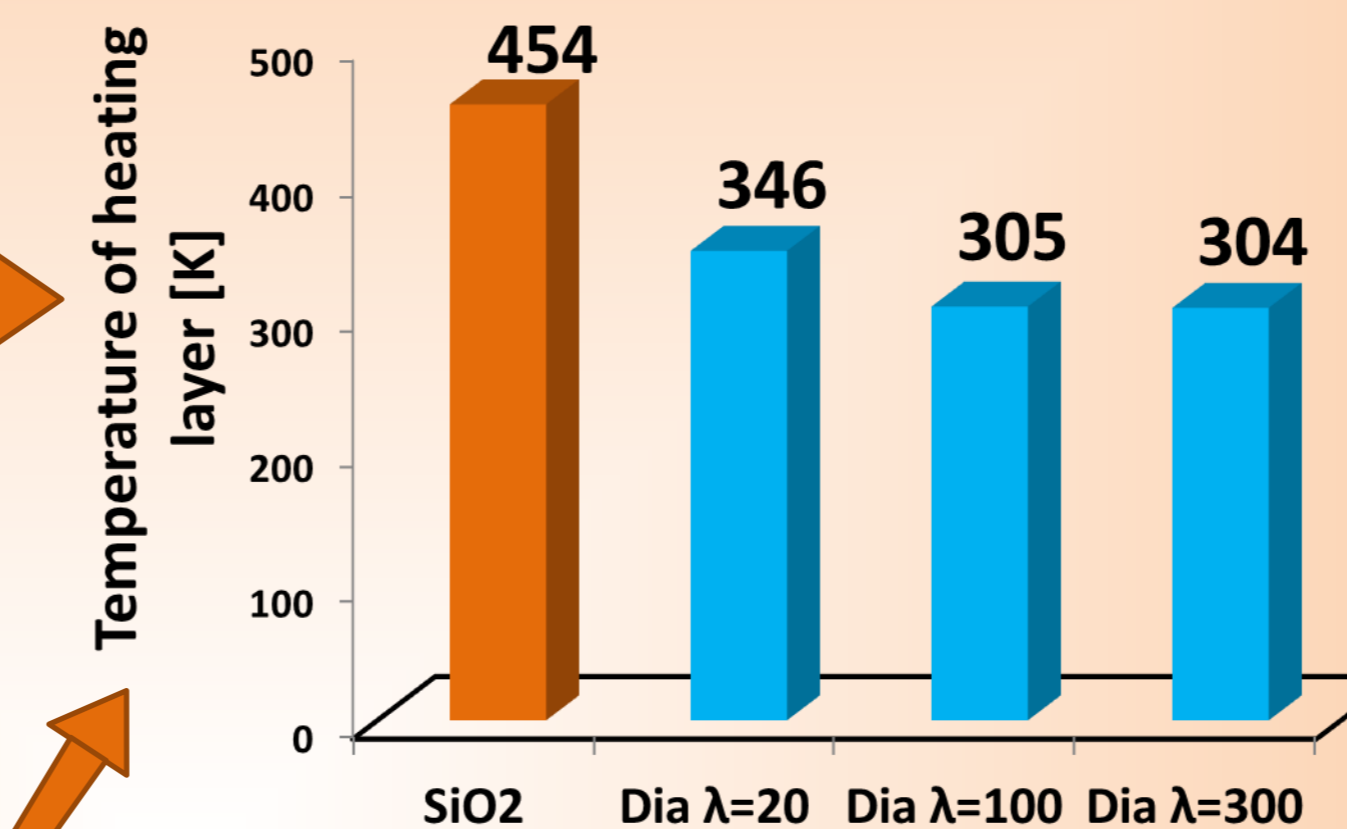
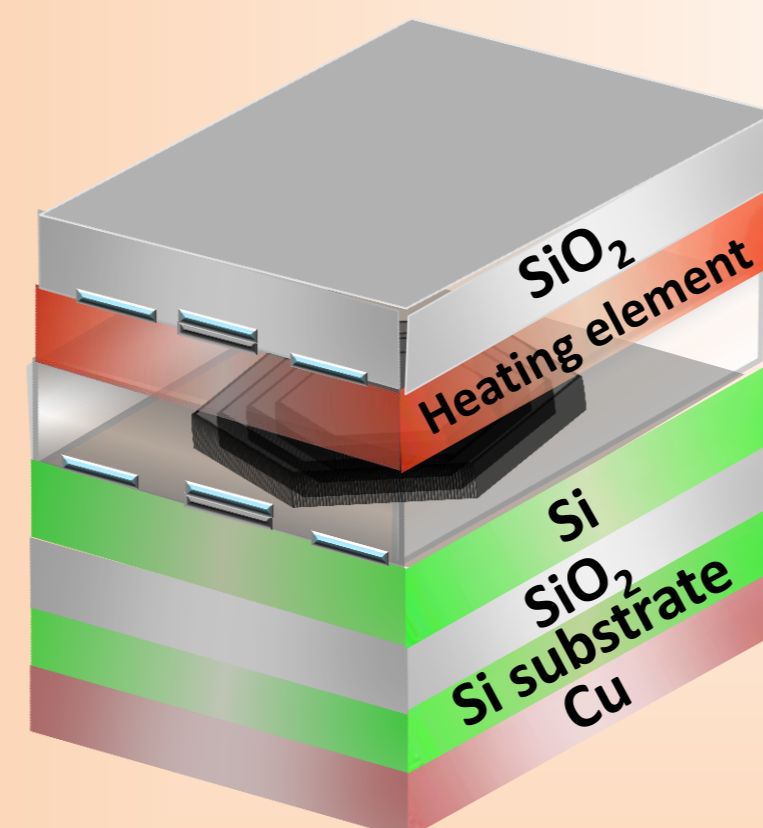
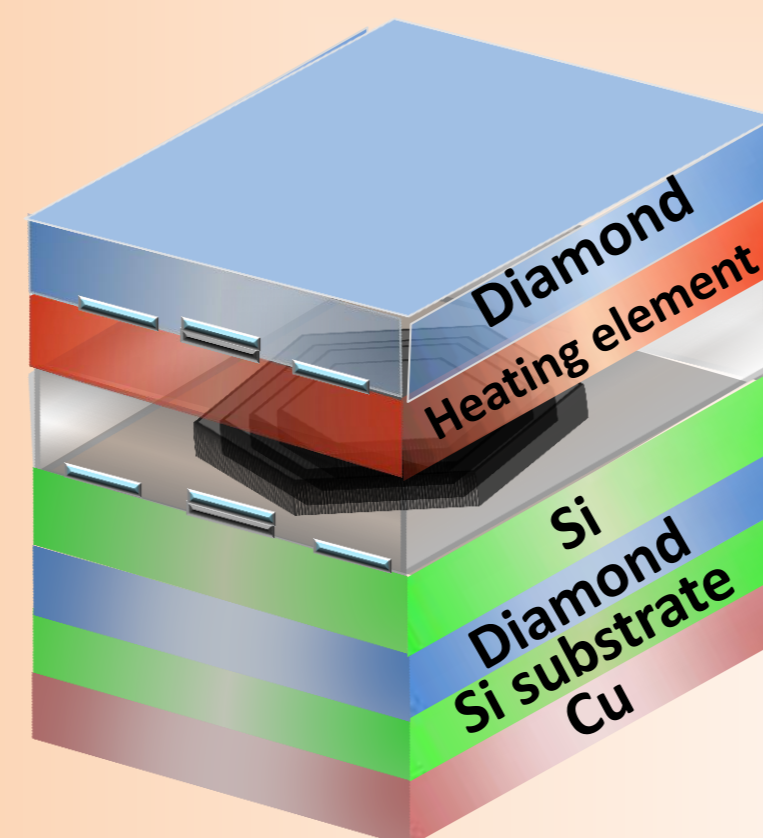
### 3D stacking structure

#### Heat insulation & Exhausting heat

Thick SiO<sub>2</sub> with glass interposer



## Simulation & Results



## Conclusions & Future work

- ✚ Heat insulation and Exhausting heat are important factor for 3D stacking structure
- ✚ Thin diamond film can realize exhaust heat and thick insulator can realize heat insulation
- ✚ Fabrication of 3D stacking structure